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**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Koichi KANAYA et al.

Group Art Unit: 1762

•Application No.: 10/565,653

Examiner: K. CHEN

Filed: January 24, 2006

Docket No.: 126247

For: VAPOR DEPOSITION APPARATUS AND VAPOR DEPOSITION METHOD

**AMENDMENT UNDER 37 CFR §1.111**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the January 14, 2009 Office Action and the April 2 personal interview,  
please consider the following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**